

IN THE CLAIMS

Please amend the claims as follows:

Claims 1-35 (Canceled).

Claim 36 (Previously Presented): A process according to Claim 68, including a step of deactivating at least one of said nozzles with respect to a direction of advance.

Claims 37-39 (Cancelled).

Claim 40 (Previously Presented): A process according to Claim 67, including a step of providing a relative movement between the plasma and the substrate parallel to the edge of the substrate.

Claims 41-43 (Cancelled).

Claim 44 (Previously Presented): A process according to Claim 68, wherein the plasma is also used to remove the coating from end edges or faces of the substrate, wherein the plasma beams are directed essentially in the normal direction onto the end edges or faces.

Claims 45-46 (Cancelled).

Claim 47 (Previously Presented) A process according to Claim 68, wherein particles which are detached in the working region are immediately removed by a discharge device.

Claim 48 (Cancelled).

Claim 49 (Previously Presented): A process according to Claim 68, used to remove metal, oxide, nitride or organic coatings or combinations of the layer types.

Claim 50 (Previously Presented): A process according to Claim 68, used to remove hydrophobic and/or hydrophilic coatings.

Claims 51-66 (Cancelled).

Claim 67 (Currently Amended): A process for removing a coating from coated substrates, while preparing the substrates for subsequent uses in which a surface of the substrate that has been at least partially freed of coating is required, comprising the steps of:

arranging a plurality of nozzles, at least one of which is slit shaped, to direct a plasma onto a region of the surface of a substrate from which a coating is to be removed, wherein the at least one slit shaped nozzle is set such that the direction of elongation of the slit has a certain orientation direction on the surface of the substrate;

directing a plasma onto the region of the surface of the substrate from which a coating is to be removed with the at least one slit shaped nozzle set such that the direction of elongation of the slit has the certain orientation direction on the surface of the substrate; and

producing a linear relative movement in a certain direction between the nozzles, including the at least one slit shaped nozzle set such that the direction of elongation of the slit has the certain orientation direction on the surface of the substrate, and the substrate to thereby remove a coating from the substrate over a width/area determined by an angle of the

certain orientation of the least one of the slit shaped nozzles relative to the certain direction of the relative movement; and

controlling the plasma to remove the coating to a desired depth.

Claim 68 (Currently Amended): A process for removing a coating from coated substrates, while preparing the substrates for subsequent uses in which a surface of the substrate that has been at least partially freed of coating is required, comprising:

directing a plasma onto a region of a substrate from which a coating is to be removed using a plurality of nozzles arranged in a row, to locally remove the coating, wherein the plasma has an effective width/area determined by number and/or shape of the nozzles;

producing a relative movement between the plasma and the substrate, parallel to the edge of the substrate;

pivoting the row of nozzles about an axis perpendicular to the substrate in the region of a corner of the substrate; ~~and~~

producing a relative movement between the plasma and the substrate, parallel to another edge of the substrate; and

controlling the plasma to remove the coating to a desired depth.

Claim 69 (Currently Amended): A process for removing a coating from coated substrates, while preparing the substrates for subsequent uses in which a surface of the substrate that has been at least partially freed of coating is required, comprising the steps of:

directing a plasma onto a region of a substrate from which a coating is to be removed using a slit shaped nozzle set at a certain rotational angle about an axis of rotation perpendicular to the substrate, to locally remove the coating;

producing a relative movement between the plasma and the substrate, parallel to a first edge of the substrate, wherein a width of the removed coating in a direction perpendicular to the direction parallel to the first edge of the substrate corresponds to the width of the slit shaped nozzle in the direction perpendicular to the direction parallel to the first edge of the substrate;

pivoting the slit shaped nozzle to another rotational angle about the axis of rotation that is perpendicular to the substrate in the region of a corner of the substrate where the first edge of the substrate joins another edge of the substrate; ~~and~~

producing a relative movement between the plasma and the substrate, parallel to the another edge of the substrate, wherein a width of the removed coating in a direction perpendicular to the direction parallel to the another edge of the substrate corresponds to the width of the slit shaped nozzle in the direction perpendicular to the direction parallel to the another edge of the substrate; and

controlling the plasma to remove the coating to a desired depth.

Claim 70 (Cancelled).